

Application/Control No.	Applicant(s)/Patent under Reexamination OSTOJA STARZEWSKI ET AL.	
10/667,980		
Examiner	Art Unit	
Caixia Lu	1713	

SEARCHED					
Class	Subclass	Date	Examiner		
526	160	1/10/65	C		
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INTERFERENCE SEARCHED					
Class	Subclass	Date	Examiner		
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SEARCH NOTES (INCLUDING SEARCH STRATEGY)				
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